EARLY DIAPHRAGM pressure sensors were described by Borky (Air Force Institute of Technology) and Wise (University of Michigan) in 1979. These mechanical sensors were based on the piezoresistive effect in silicon, a basic approach found in a wide range of commercial automotive, industrial, and biomedical microsensors.

J.M. Borky
Air Force Institute of Technology, Wright-Patterson AFB, OH

K.D. Wise
University of Michigan, Ann Arbor, MI